

Notice of References Cited	Application/Control No. 10/518,602	Applicant(s)/Patent Under Reexamination ANDO ET AL.	
	Examiner Matthew Landau	Art Unit 2815	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,521,998	02-2003	Teraguchi et al.	257/745
	B	US-2003/0109088	06-2003	Nishii et al.	438/167
	C	US-2003/0107065	06-2003	Taniguchi et al.	257/289
	D	US-4,951,121	08-1990	Furukawa et al.	257/751
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	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kim et al., "High-temperature structural behavior of Ni/Au Contact on GaN(0001)", MRS Internet Journal: Nitride Semiconductor Research, 2/15/2001
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.